

MOS Field-Effect Transistors (MOSFETs)

Microelectronic Circuits - Fifth Edition Sedra/Smith 2004

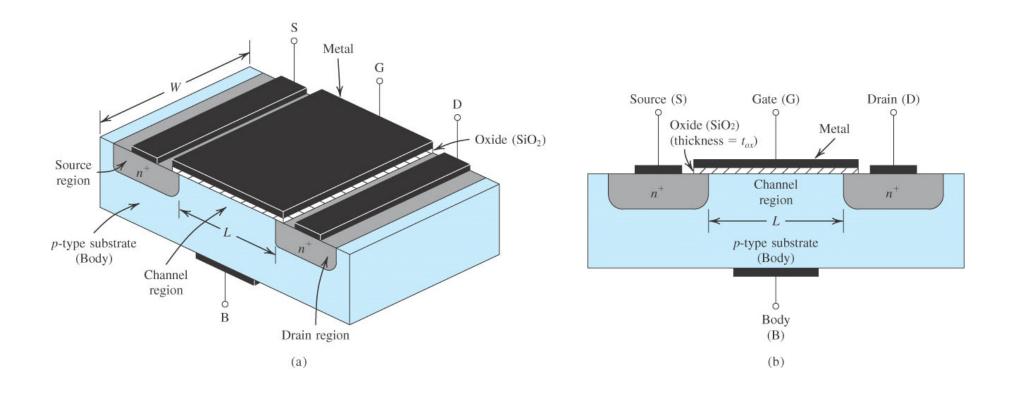


Figure 4.1 Physical structure of the enhancement-type NMOS transistor: (a) perspective view; (b) cross-section. Typically L = 0.1 to 3 μ m, W = 0.2 to 100 μ m, and the thickness of the oxide layer (t_{ox}) is in the range of 2 to 50 nm.

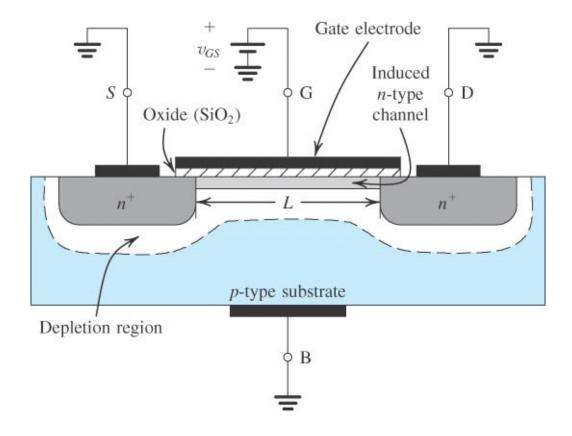


Figure 4.2 The enhancement-type NMOS transistor with a positive voltage applied to the gate. An *n* channel is induced at the top of the substrate beneath the gate.

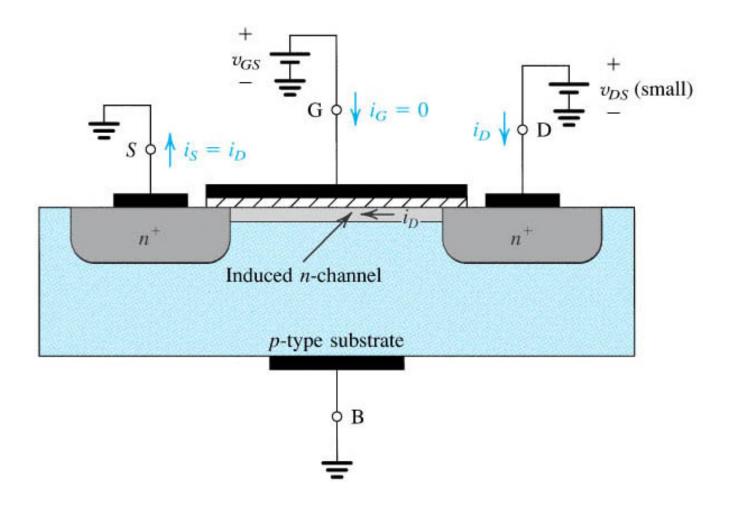


Figure 4.3 An NMOS transistor with $v_{GS} > V_t$ and with a small v_{DS} applied. The device acts as a resistance whose value is determined by v_{GS} . Specifically, the channel conductance is proportional to $v_{GS} - V_t$ and thus i_D is proportional to $(v_{GS} - V_t) v_{DS}$. Note that the depletion region is not shown (for simplicity).

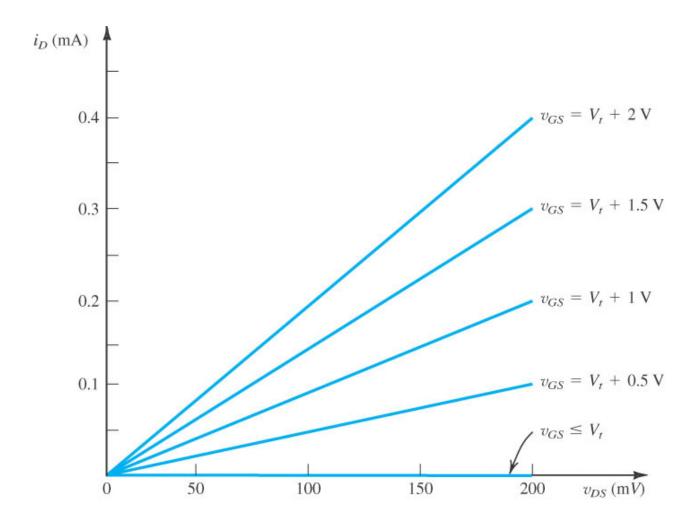


Figure 4.4 The i_D – v_{DS} characteristics of the MOSFET in Fig. 4.3 when the voltage applied between drain and source, v_{DS} , is kept small. The device operates as a linear resistor whose value is controlled by v_{GS} .

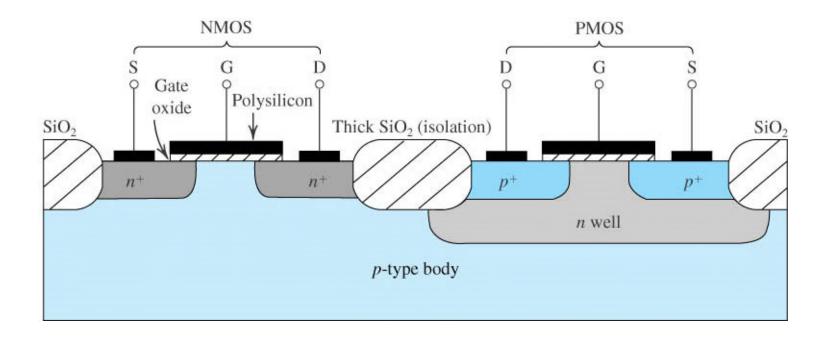


Figure 4.9 Cross-section of a CMOS integrated circuit. Note that the PMOS transistor is formed in a separate *n*-type region, known as an *n* well. Another arrangement is also possible in which an *n*-type body is used and the *n* device is formed in a *p* well. Not shown are the connections made to the *p*-type body and to the *n* well; the latter functions as the body terminal for the *p*-channel device.